

FIG. 1

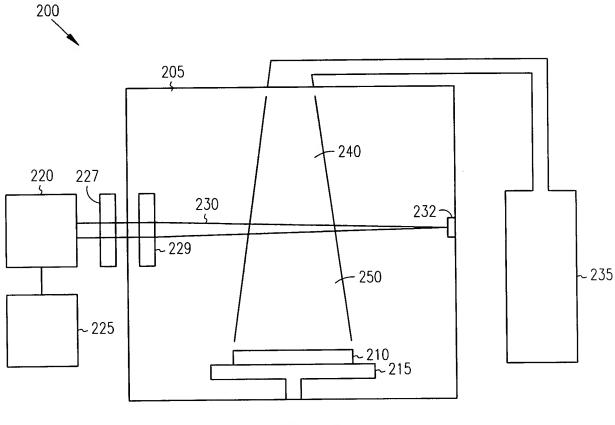


FIG. 2

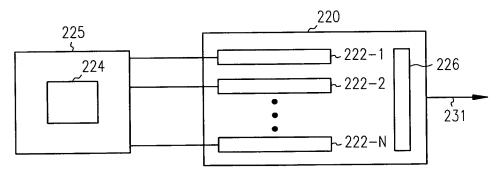


FIG. 3

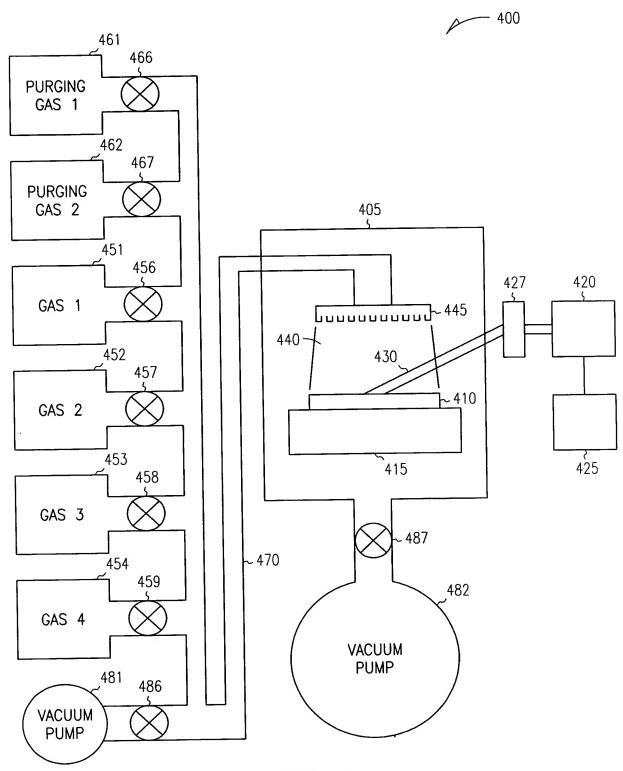


FIG. 4

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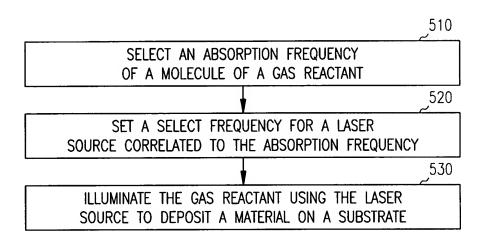


FIG. 5

MEASURE ABSORPTION FREQUENCIES OF
ONE OR MORE MOLECULES OF A GAS FLOW

SELECT AN ABSORPTION FREQUENCY AT WHICH
TO ACTIVATE A GAS PRECURSOR IN THE GAS FLOW

TRIGGER A LASER OF A LASER ARRAY WHERE
THE TRIGGERED LASER HAS A FREQUENCY CORRESPONDING
TO THE SELECTED ABSORPTION FREQUENCY

EXPOSE THE GAS FLOW TO A LASER BEAM FROM THE
TRIGGERED LASER TO DEPOSIT A MATERIAL ON A SUBSTRATE

FIG. 6



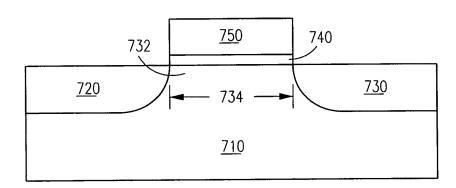


FIG. 7

TITLE: LASER ASSISTED MATERIAL DEPOSITION INVENTORS NAME: Ross S. Dando et al.

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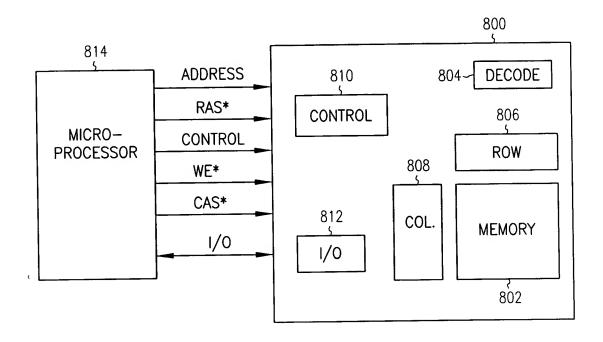


FIG. 8

